

Abstract of the Disclosure

An object of the present invention is to grasp
easily a process history of a target object such as a
5 semiconductor wafer. The processing apparatus of the
present invention includes: a processing apparatus body
which includes a plurality of process units for
executing a prescribed process to a target object, and
transport mechanism for transporting said target object
10 between the process units; a first controller for
controlling the processing apparatus as a whole; a
second controller for controlling the process units; an
information storage section for taking in a signal
transmitted and received between the first and second
15 controllers; and a host computer for monitoring
operation states of the process units. The present
invention is extended to a processing system including
a plurality of the processing apparatuses connected
with a host computer which is further connected with a
20 monitor computer through a communication network.